

KLA-Tencor 全新光罩檢測功能系統 可排除 130-NM 晶圓良率下降的主要

KLA-Tencor Nasdaq KLAC TeraStar™
TeraFlux™ 130-nm IC
contact
via
defective contact
TeraFlux

IC optical
proximity correction OPC embedded phase shift mask
248-nm 130-nm
optical lithography
pattern 130 nm

contact via CD IC

KLA-Tencor Lance Glasser
TeraStar 40% TeraFlux
248-nm 193-nm =

TeraFlux

5.5%
130-nm
KLA-Tencor

110-nm

die-to-die
TeraStar
die-to-database
TeraFlux

KLA-Tencor
TeraFlux

6%

130-nm

TeraFlux